IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:

Takahiko KAWATANI

Serial No.:

NEW

Filed:

March 4, 2004

For:

DOCUMENT AND PATTERN CLUSTERING METHOD AND APPARATUS

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents P. O. Box 1450 Alexandria, VA 22313-1450

March 4, 2004

Sir:

In accordance with the provisions of 37 C.F.R. §1.56, §1.97 and §1.98, the Examiner's attention is directed to the documents listed on the attached Form PTO-1449. It is respectfully requested that the listed documents be expressly considered during prosecution and that the documents be made of record therein and appear among the "References Cited" on any patent issuing from the above-identified application. This Information Disclosure Statement is being filed together with the present application. No certification or fee is required.

Respectfully submitted,

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INFORMATION DISCLOSURE			ATTY. DOCKET NO. 1509-477		SERIAL NO. NEW	
	CITATION APPLICA	I IN AN	APPLICANT Takahiko KAWATANI			
(PTO-1449)			FILING DATE March 4, 2004		GROUP Not assigned	
		U.S. PATENT	DOCUMENTS			
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
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		FOREIGN PATE	NT DOCUMENTS			Translation
EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	Yes No
		R ART (Including Author				405 529
	MANNING et al., Foundations of Statistical Natural Language Processing, Chapter 14, pp. 495-528, 1999, The MIT Press.					
*	Proceedings of the	ment Clustering with Clus 25th Annual Internationa val, August 2002, pp. 191-	I ACM-SIGIR Confe	erence on Re	ction Capabiliti esearch and Dev	es," velopment in
EXAMINER			DATE CONSIDE	RED		

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

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